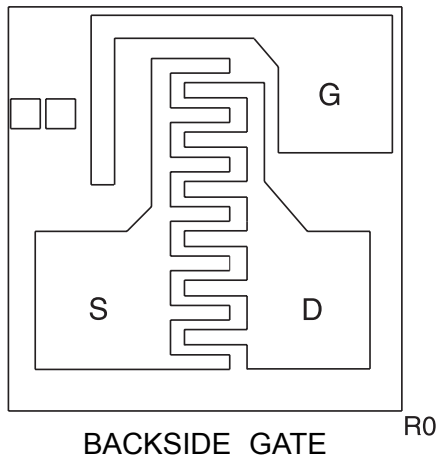


PROCESS DETAILS

Process	EPITAXIAL PLANAR
Die Size	15 x 15 MILS
Die Thickness	8.0 MILS
Drain Bonding Pad Area	3.2 X 4.0 MILS
Source Bonding Pad Area	3.2 X 4.0 MILS
Gate Bonding Pad Area	3.2 X 4.0 MILS
Top Side Metalization	Al - 30,000Å
Back Side Metalization	Au - 6,000Å

GEOMETRY

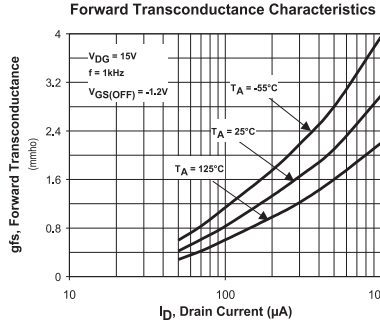
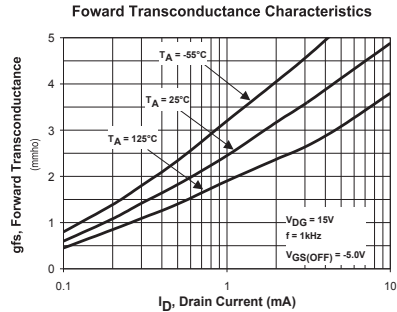
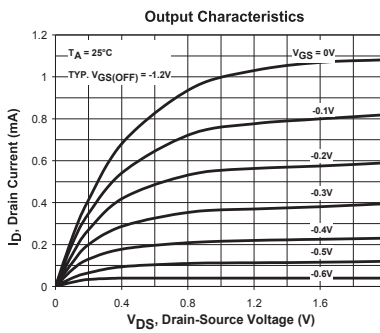
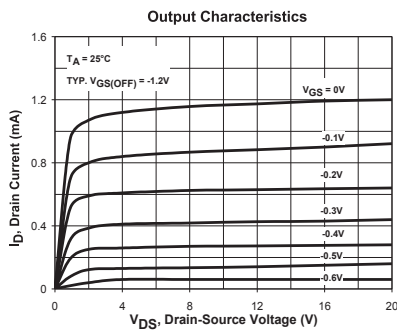
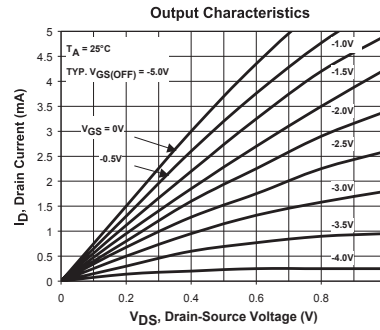
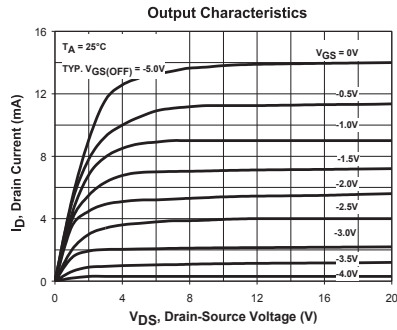


GROSS DIE PER 4 INCH WAFER
53,730

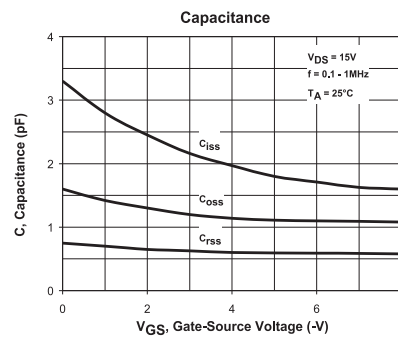
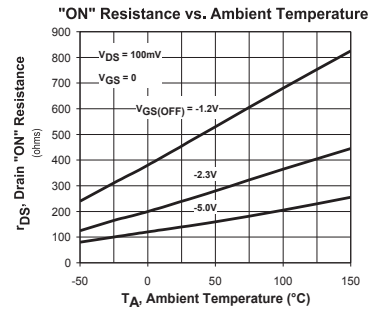
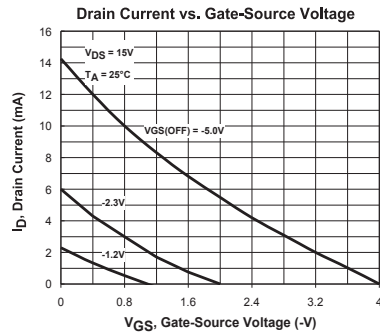
PRINCIPAL DEVICE TYPES
2N4416A
CMPF4416A

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